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Applicant

TRAVIS A. LEMKE

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Group

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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TS	3,392,493	07/1968	Hofmann et al.	-	-	
TS	3,412,325	11/1968	Soderling	-	-	
TS	3,719,090	03/1973	Hathaway	-	-	
TS	4,382,173	05/1983	Howard-Leicester	-	-	
TS	4,910,155	03/1990	Cote et al.	-	-	
TS	4,977,929	12/1990	Chinnock et al.	-	-	
X	5,272,027	12/1993	Dillenbeck et al.			
X	5,293,893	03/1994	O'Dougherty			
X	5,340,370	08/1994	Cadien et al.			
X	5,364,510	11/1994	Carpio			
X	5,447,056	09/1995	Foote			
X	5,490,611	02/1996	Bernosky et al.			
X	5,522,660	06/1996	O'Dougherty et al.			
X	5,632,960	05/1997	Ferri, Jr. et al.			
X	5,647,989	07/1997	Hayashi et al.			
X	5,664,990	09/1997	Adams et al.			
X	5,755,614	05/1998	Adams et al.			

FOREIGN PATENT DOCUMENTS

Name	Document Number	Date	Country	Class	Subclass	Translation Yes/No
X	0 605 395	6 July 1994	EP			
X	0 714 054	29 May 1996	EP			
X	62 11520	7 October 1985	JP			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

X	Adams, et al., <i>CMP Slurry Reprocessing</i> , 6 pp. X cited on sheet 1
X	Philipossian, et al., "An Overview of Current Issues and Future Trends in CMP Consumables," Proceedings of the First CMP-MIC Conference, February 1996, pp. 13-19. X
X	J. P. Bare, "Improved Analytical Technique for Metal CMP Slurry," Proceedings of 2 nd CMP-MIC Conference, February 1997, pp. 405-408. X

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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NOTE: ~~X~~ cited on sheet 1

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